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**Date:** September 18, 2003

**TO:** Office of Initial Patent Examination's  
Filing Receipt Corrections

**FACSIMILE NO.:** (703) 746-9195

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**Re:** Filing Receipt for  
U.S. Patent Application No. 10/600,775  
THIN MAGNETRON STRUCTURES FOR PLASMA GENERATION IN  
ION IMPLANTATION SYSTEMS  
Filing Date: June 20, 2003  
Inventor: Benveniste et al.  
Our Ref.: EATNP145US

Attached is a copy of page 1 of the Filing Receipt for the above-referenced application. The last name of the first inventor is misspelled. The name is circled and the correct spelling is 'Benveniste'.

PAGES TRANSMITTED INCLUDING THIS PAGE 2

EATNP/4505



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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/600,775	06/20/2003	2821	1236	02-IMP-059	14	47	3

CONFIRMATION NO. 5945

29393  
ESCHWEILER & ASSOCIATES, LLC  
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## FILING RECEIPT



\*OC000000010873588\*

Date Mailed: 09/15/2003

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Receipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

## Applicant(s)

Benveniste  
Victor M. Benveniste, Gloucester, MA;  
William F. DiVergilio, Beverly, MA;  
Bo H. Vanderberg, Gloucester, MA;

## Domestic Priority data as claimed by applicant

This appln claims benefit of 60/470,926 05/15/2003

## Foreign Applications

If Required, Foreign Filing License Granted: 09/12/2003

Projected Publication Date: 11/18/2004

Non-Publication Request: No

Early Publication Request: No

## Title

Thin magnetron structures for plasma generation in ion implantation systems

